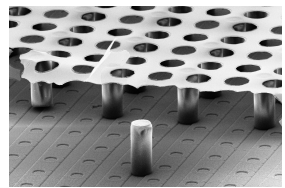
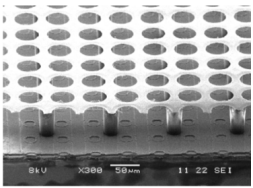


InGrids / GridPixes

Jochen Kaminski

University of Bonn

Industry-Academia Matching Event on MPGD
Annecy
26./27. April 2012



Content

I. What are InGrids, GridPixes, GEMGrids, ... ?

- From Micromegas to InGrids
- The Beginning of InGrids
- Nomenclature

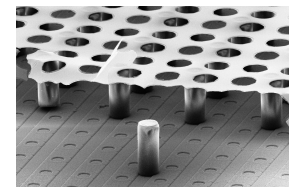
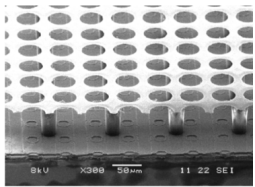
II. The Ingredients: Chip, Protection Layer, Grid, Detector, ...

- Timepix, Readout Electronics, Software
- Production of grids
- Protection layer
- Some results
- Wafer-scale production

III. Application in Academia with performance

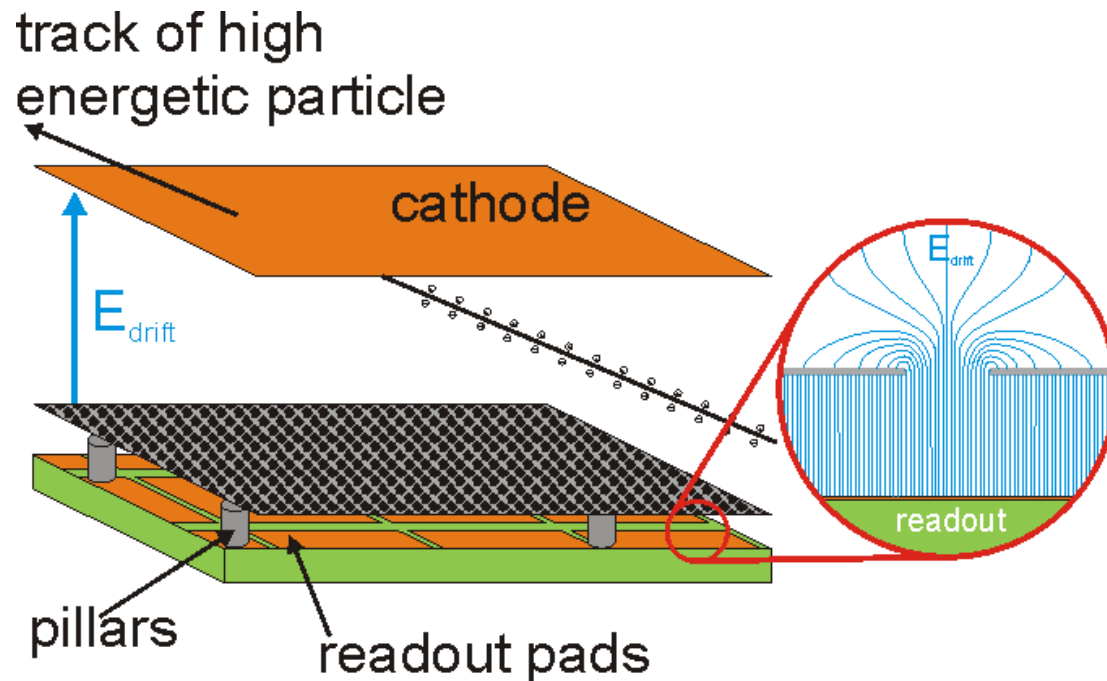
- CAST - low background, good energy resolution
- LCTPC – good spatial resolution

IV. Summary and Acknowledgment



From Micromegas to InGrids

Invented by Y. Giomataris, et al. (NIMA 376, p. 29-35, 1995)



Two stage parallel plate detector:

- Ionization in drift volume
- Gas amplification in thin gap with high electric field

Standard charge collection:

- Pads of several mm^2
- Long strips ($l \sim 10 \text{ cm}$, pitch $\sim 200 \mu\text{m}$)

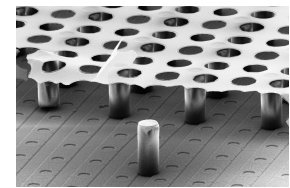
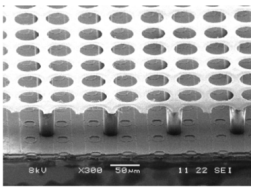
Could the spatial resolution of single electrons be improved?

$$\text{Ar:CO}_2 \text{ 70:30} \rightarrow D_t = 187 \mu\text{m}/\sqrt{\text{cm}} \rightarrow \sigma = 21 \mu\text{m}$$

$$\text{Ar:CH}_4 \text{ 90:10} \rightarrow D_t = 208 \mu\text{m}/\sqrt{\text{cm}} \rightarrow \sigma = 24 \mu\text{m}$$

$$\text{Ar:iButan 95:5} \rightarrow D_t = 211 \mu\text{m}/\sqrt{\text{cm}} \rightarrow \sigma = 24 \mu\text{m}$$

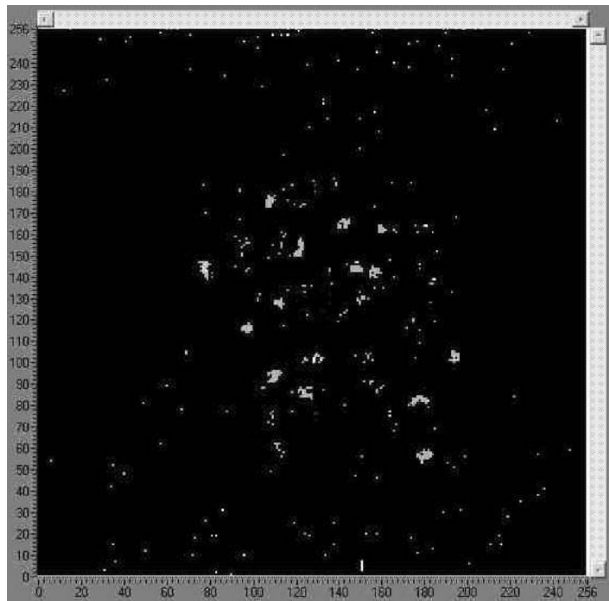
Smaller pads/pixels could result in better resolution!



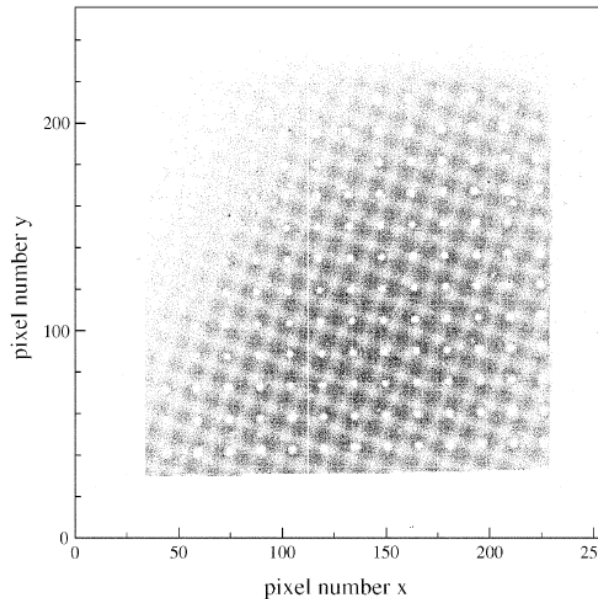
The Beginning of InGrids

Two groups studied the use of pixel readout chip in MPGDs:

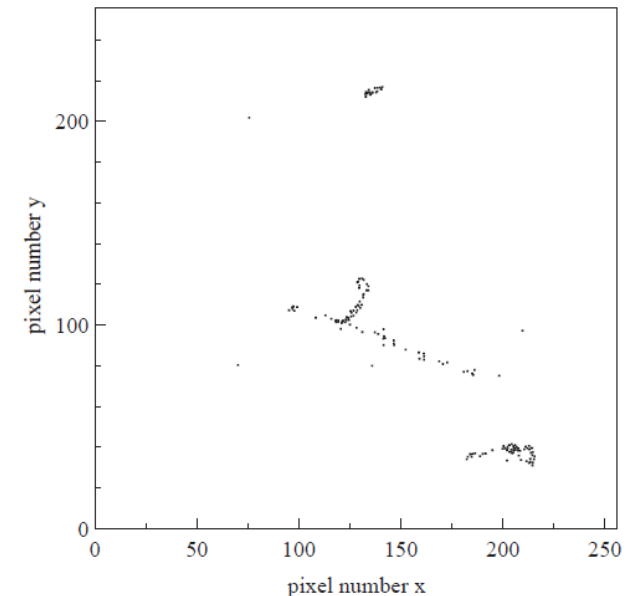
- 1.) R. Bellazzini, GEMs + VLSI Chip (NIMA 535, pp. 477, 2004)
- 2.) H. v.d.Graaf, GEMs/Micromegas with Medipix2
(NIMA 535, pp. 506, 2004, NIMA 540, pp. 295, 2005)



Event showing conversions
of several γ from ^{55}Fe

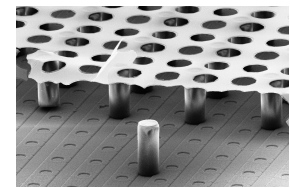
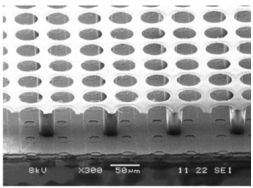


Occupancy showing
Moire-effect



Cosmic rays with a δ -electron

Need better alignment of pixels and grid holes – best: one hole / pixel
Achievable with modern postprocessing methods



Nomenclature

Timepix / Medipix2: CMOS-ASIC designed by the Medipix collaboration, originally planned as an imaging chip for medical applications (NIMA 581, pp. 485, 2006)

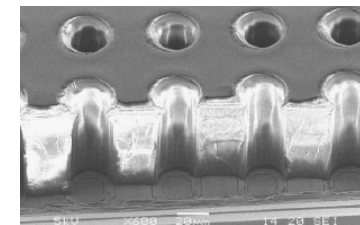
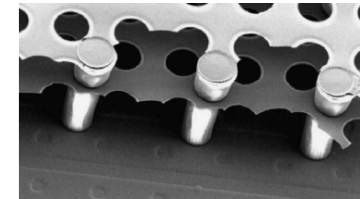
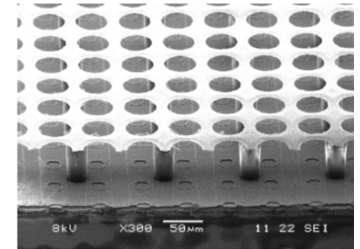
InGrid: Integrated Grid: Micromegas structure built on top of pixel chip with industrial postprocessing techniques (NIMA 556, pp. 490, 2006)

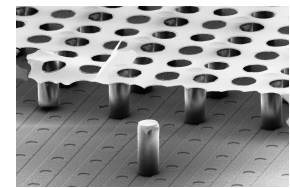
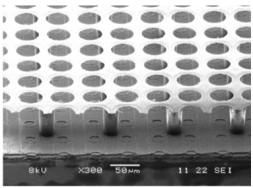
GridPix: complete detector based on InGrids + Pixel chip including cathode, gas volume etc.

TwinGrid: two grids on top of each other (NIMA 610, pp. 644, 2009)

GEMGrid: Same as InGrid, but grid rests on solid layer with holes, instead of pillars (NIMA 608, pp. 96, 2009)

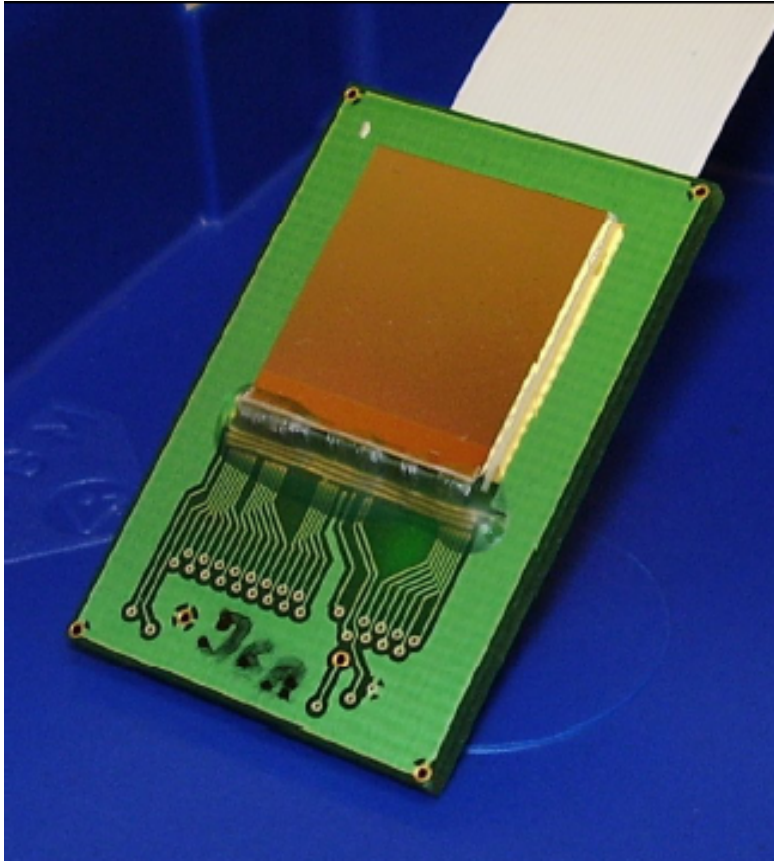
Gossip: Gas On Slimmed Silicon Pixels, a very thin GridPix detector with minimal material budget, e.g. 1 mm of gas gap, thinned ASIC





Timepix Chip

Timepix chip (1st version) derived from MediPix-2



Available for tests since Nov. 2006

Number of pixel: 256×256 pixel

Pixel pitch: $55 \times 55 \mu\text{m}^2$

Chip dimensions: $1.4 \times 1.4 \text{ cm}^2$

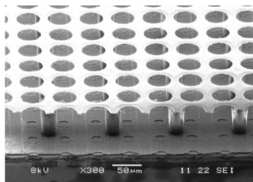
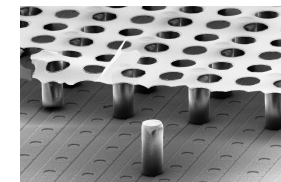
ENC: $\sim 90 e^-$

Each pixel can be set to one of these modes:

- Hit counting
- TOT = time over threshold
gives integrated charge
- Time between hit and shutter end
- Hit/no-hit

Limitations: no multi-hit capability, charge and time measurement not possible for one pixel

The successor Timepix-3 is being designed and will be submitted soon.



MUR0S 2.1 designed at NIKHEF - still in wide use today, but not in production anymore, can handle up to 8 chips, needs outdated NI card

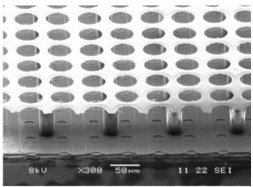
USB interface designed by TU Prague very easy to handle/transport but limited speed and functionality



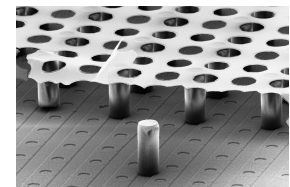
ReLaXd designed at NIKHEF – fast readout for 4 Medipix/Timepix chips

FITPix improved version of the USB-interface designed by TU Prague can handle up to 16 detectors

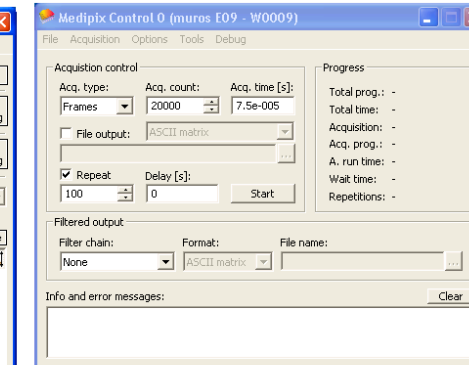
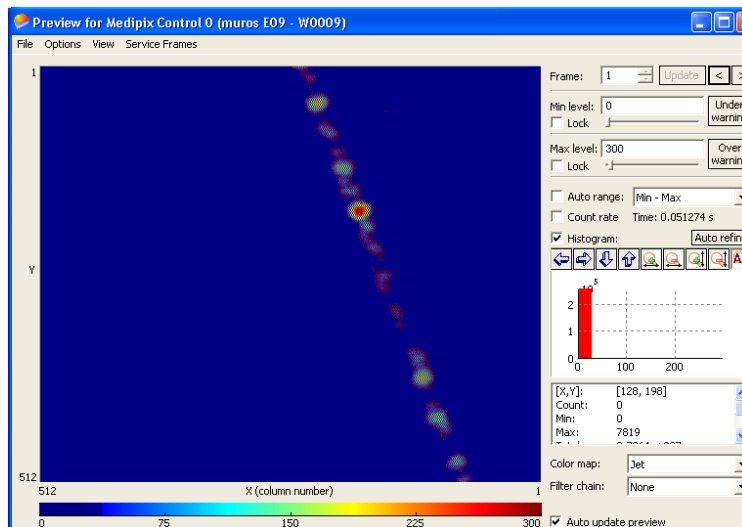
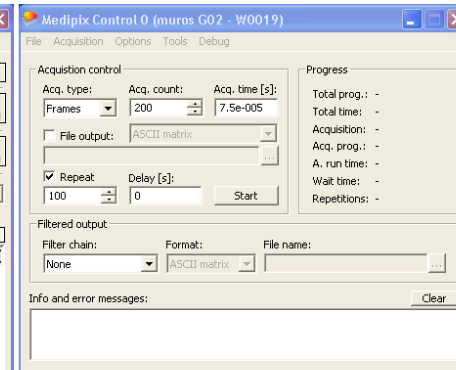
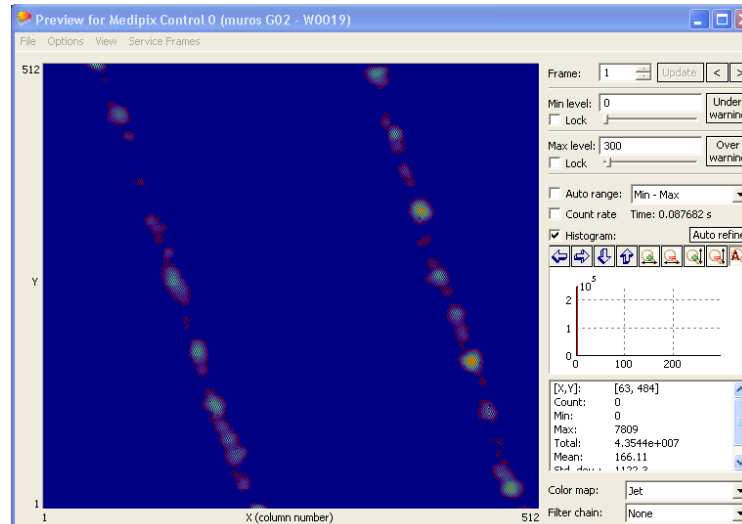


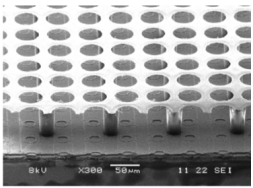


Software

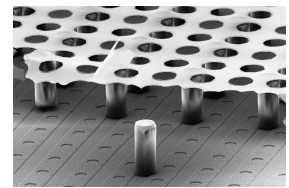
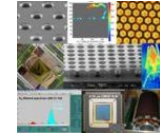


Most systems are operated by the Pixelman software developed at the TU Prague.



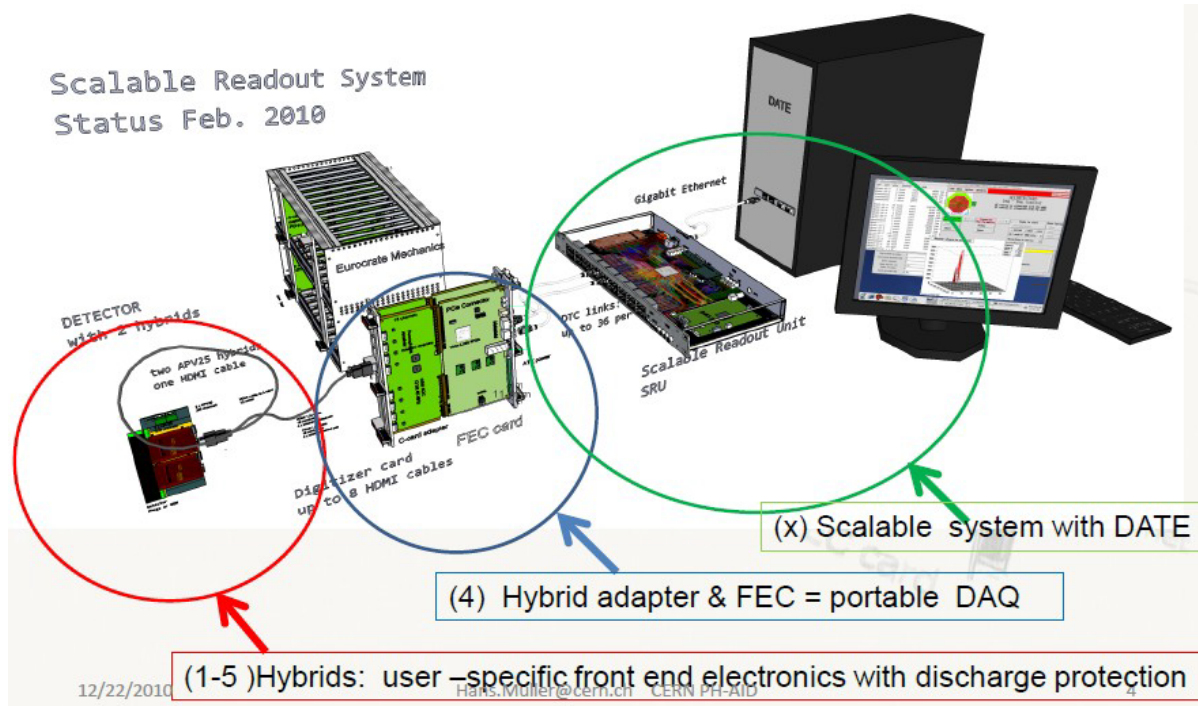


Timepix readout with SRS

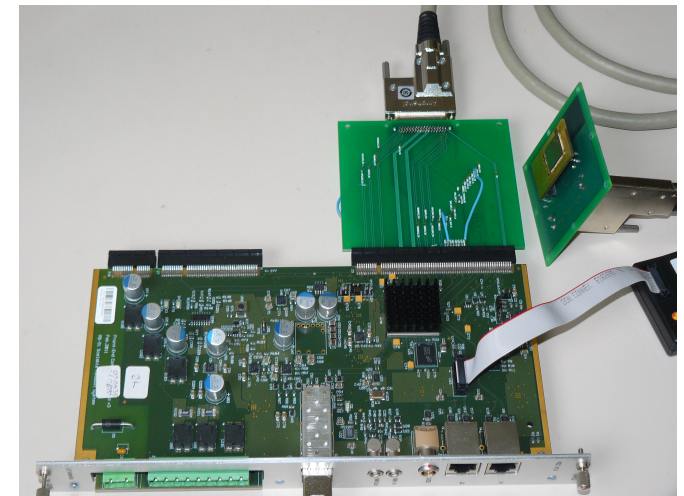


The Scalable Readout System is designed by the RD51 collaboration with CERN as a main developer. → See presentation/demonstration of H. Muller
Idea: produce a flexible readout electronics, which can handle different chips (new FPGA code, chip carrier), which many groups can use

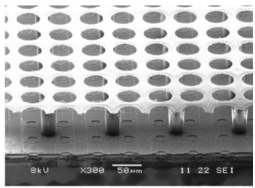
Scalable Readout System
Status Feb. 2010



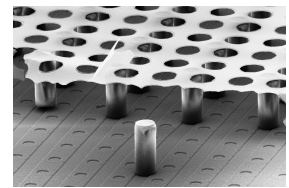
U. Bonn and U. Mainz are developing a readout for the Timepix chip



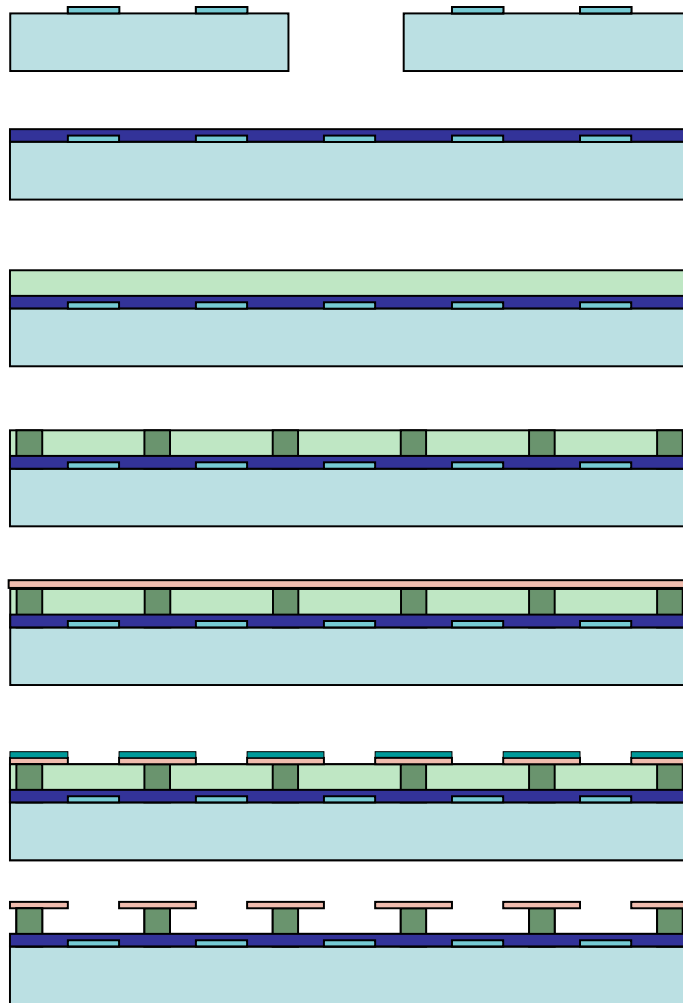
Operation has been demonstrated for a single chip, more functionality has to be added. Aim is to operate ~100 chip in 2013.



Production of InGrids



The production of InGrids was pioneered by the University of Twente/MESA+.



1. Dicing of Wafer

2. Formation of Si_xN_y protection layer

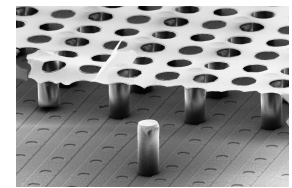
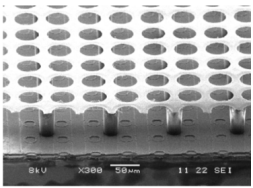
3. Deposition of SU-8

4. Pillars-like structure formation

5. Deposition of thin Al layer

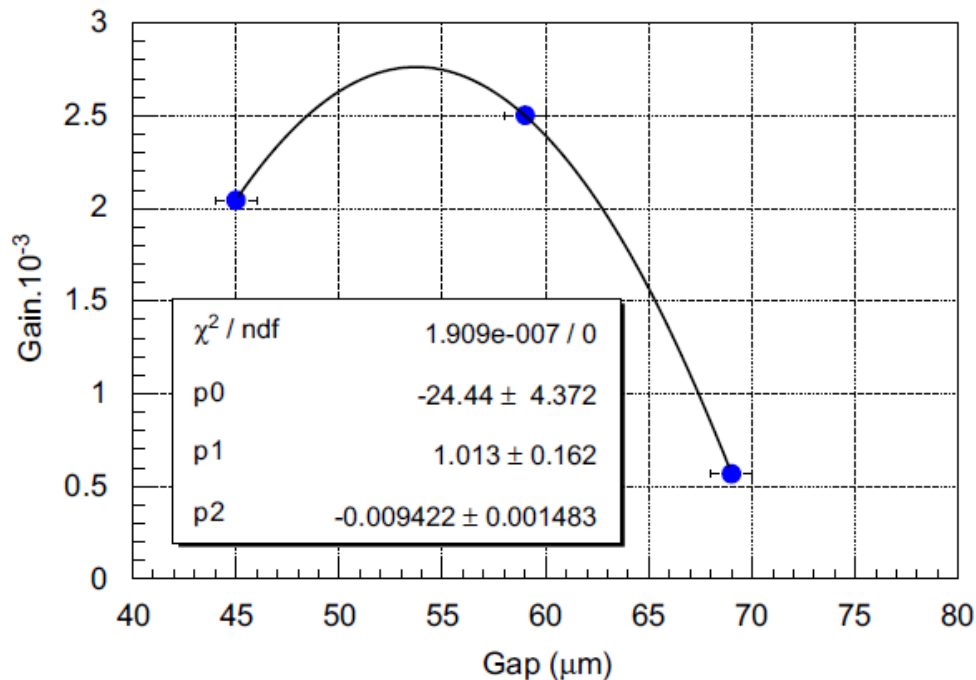
6. Formation of Al grid

7. Development of SU-8

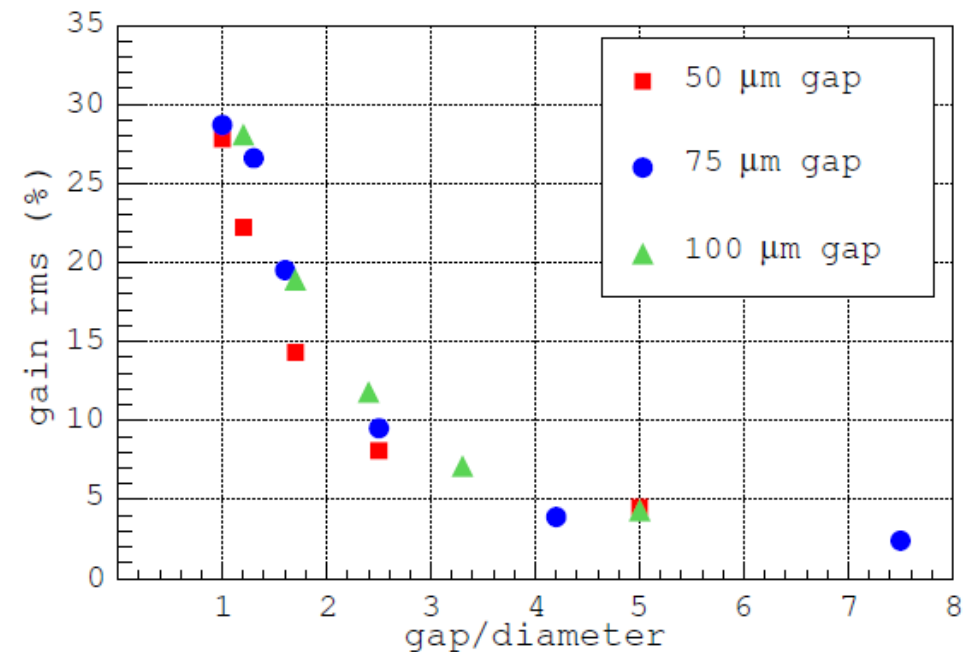


Optimization of InGrids

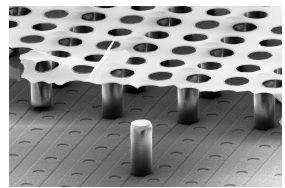
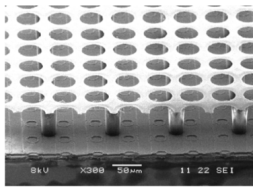
Detailed studies have been performed to optimize the layout of the structure. (NIMA 591, pp. 147, 2008, PhD. Thesis of M. Chefdeville, NIKHEF)



The influence of the gap size and hole diameters on gain, energy resolution, ion feedback and collection efficiency were measured.



Also the layout of the supporting structures (pillars and dykes) was optimized to give the highest mechanical strength.



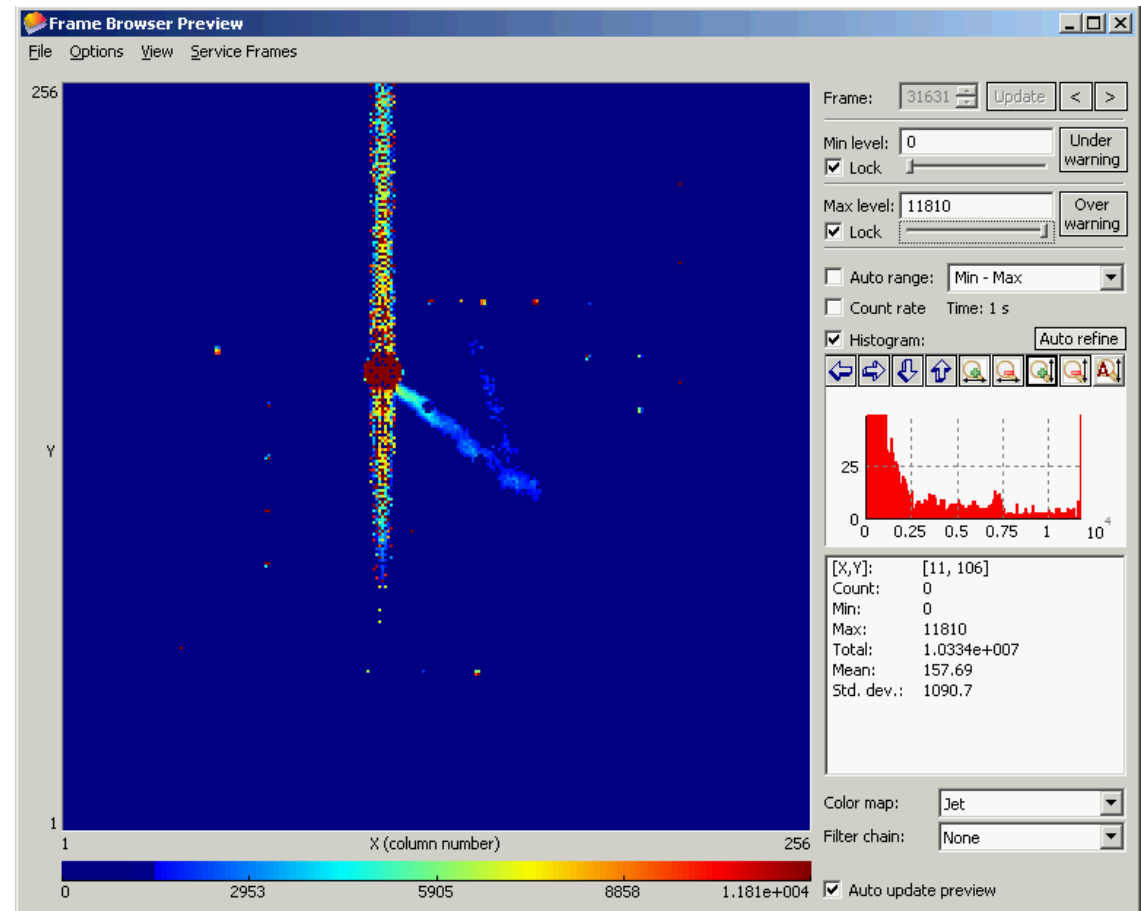
Discharge triggered for example by highly ionizing particles could easily **destroy the the chip**. The charge collected by one pixel was too high.

A protection layer is placed on the chip to **disperse the charge** on many pixels and thus lower the input current per pixels. Besides, the charge is removed slowly and thus **quenches the discharge**.

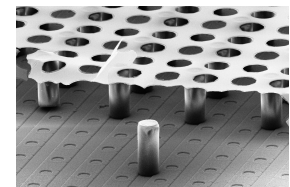
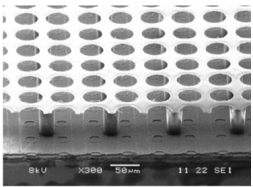
high resistive material

15 μm aSi:H ($\sim 10^{11} \Omega\cdot\text{cm}$)

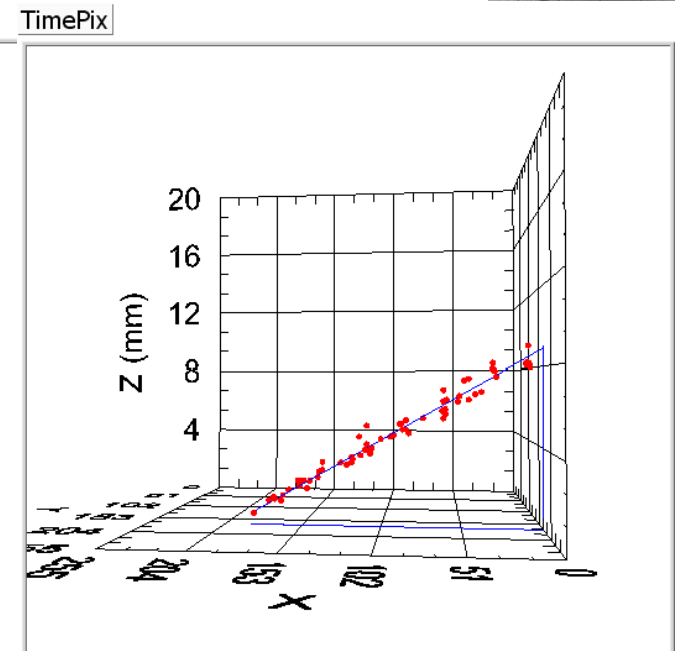
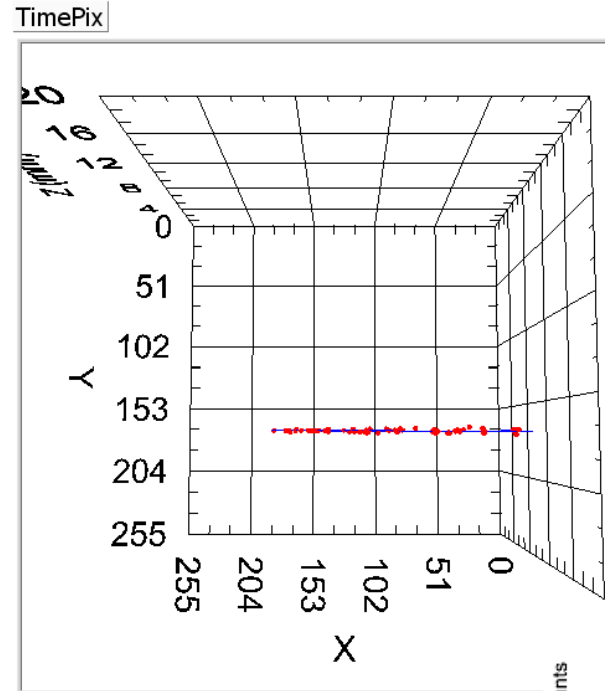
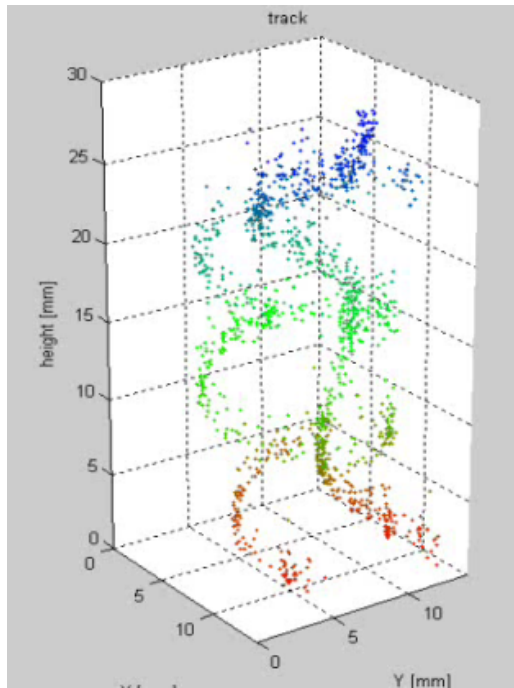
8 μm Si_XN_Y ($\sim 10^{14} \Omega\cdot\text{cm}$)



Chips survives several thousand discharges triggered by α s.



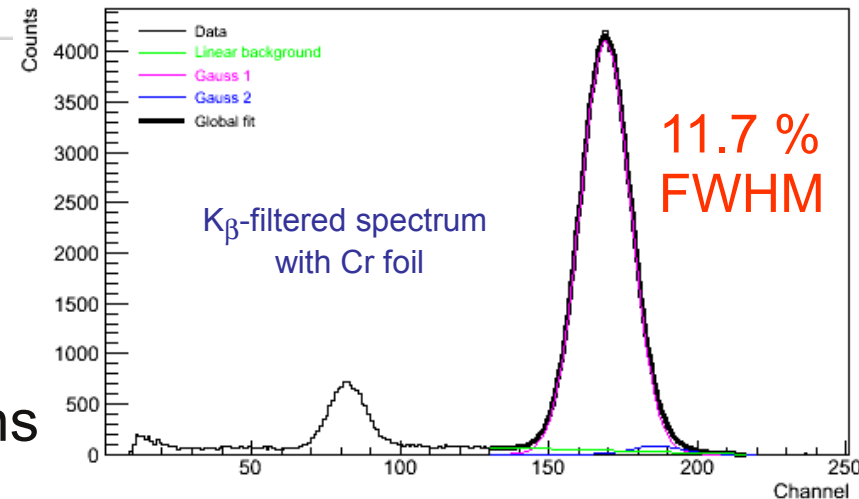
Some Results



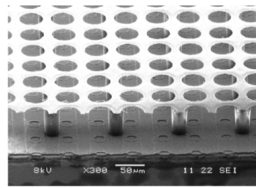
2 electrons of a ^{90}Sr source in $B = 0.2 \text{ T}$



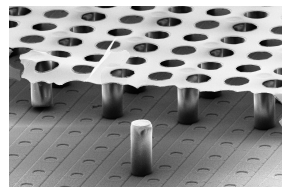
InGrids show for example:
 extremely good energy resolution
 high detection efficiency of single electrons
 (up to 98 % were reached)



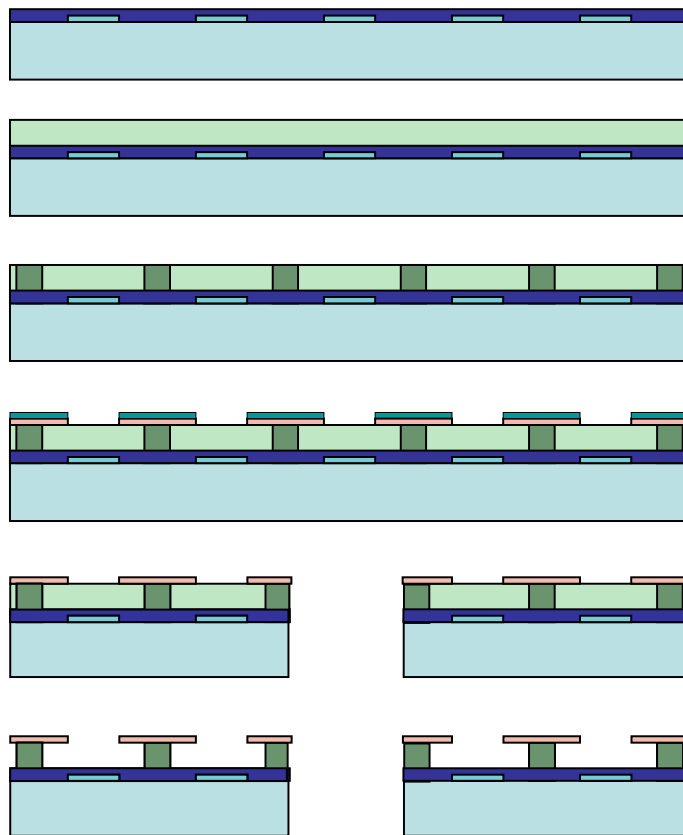
^{55}Fe spectrum in $\text{Ar}:\text{CH}_4$ 90:10



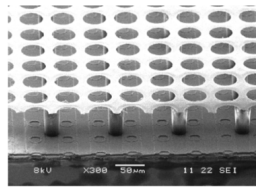
Wafer-based Production Fraunhofer IZM



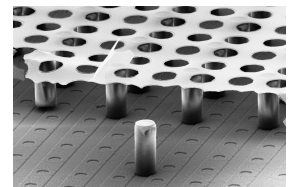
Production at Twente was based on 1 - 9 chips process.
This could not satisfy the increasing demands of R&D projects.
New production set up at the Fraunhofer Institut IZM at Berlin.
This process is wafer-based → 1 wafer (107 chips) is processed at a time.



1. Formation of Si_xN_y protection layer
2. Deposition of SU-8
3. Pillar structure formation
4. Formation of Al grid
5. Dicing of Wafer
6. Development of SU-8



Wafer-based Production



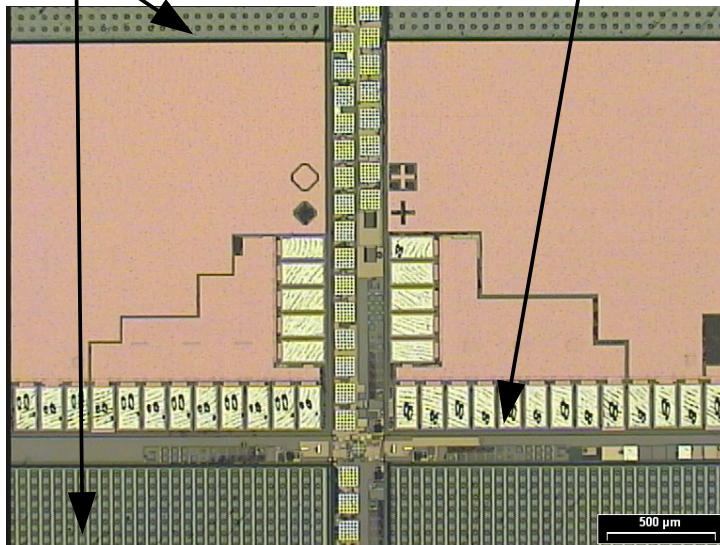
Main challenges: - Formation of layers, in particular protection layer

MESA+

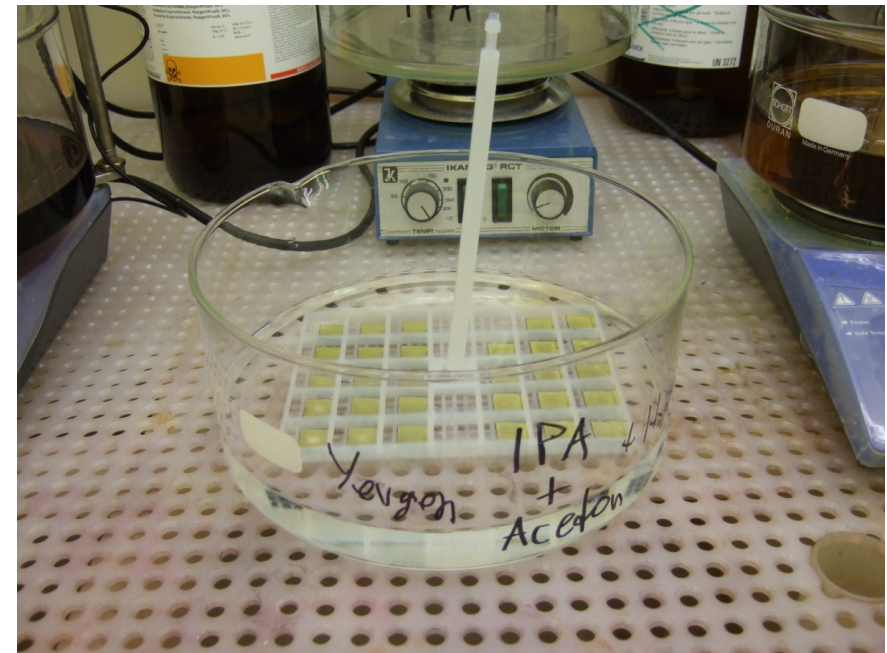
Institute for Nanotechnology

- Deposition of Al
- Final development of SU-8 → still chip-based

SiRN should not cover bond pads

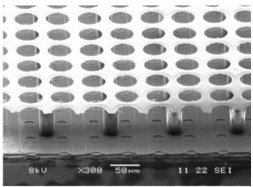


After development of pillars, the grid is too fragile for dicing

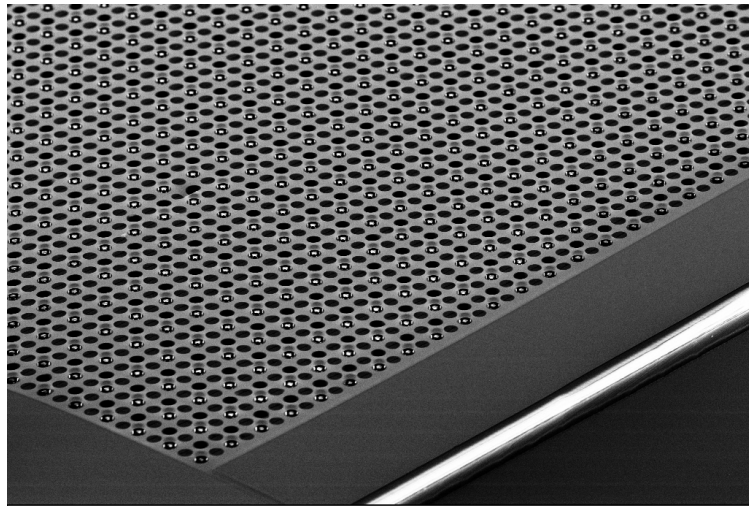
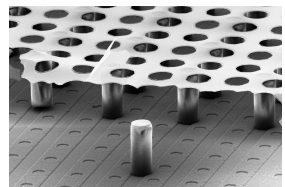


First tests: **mechanical mask**
→ failed due to thermal stress
Better: **poyimide mask** chem. removed

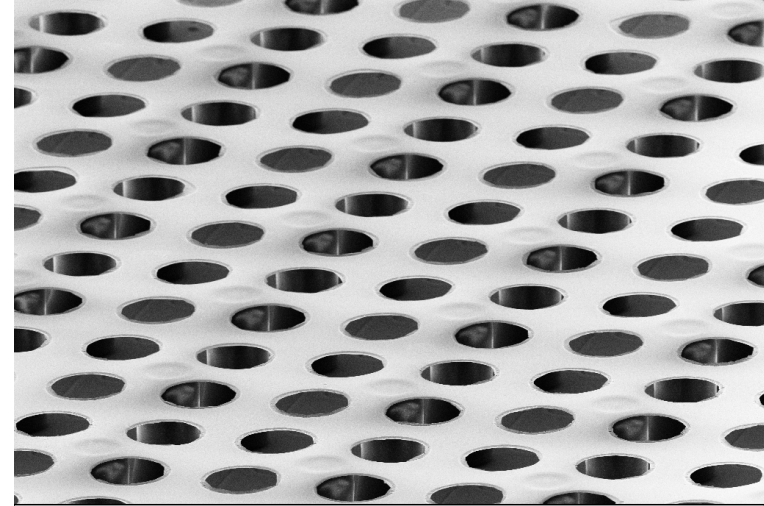
Time consuming



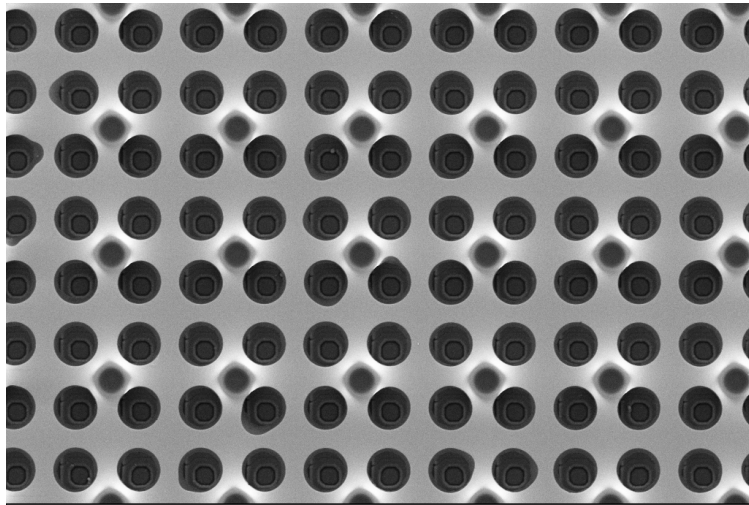
SEM Pictures



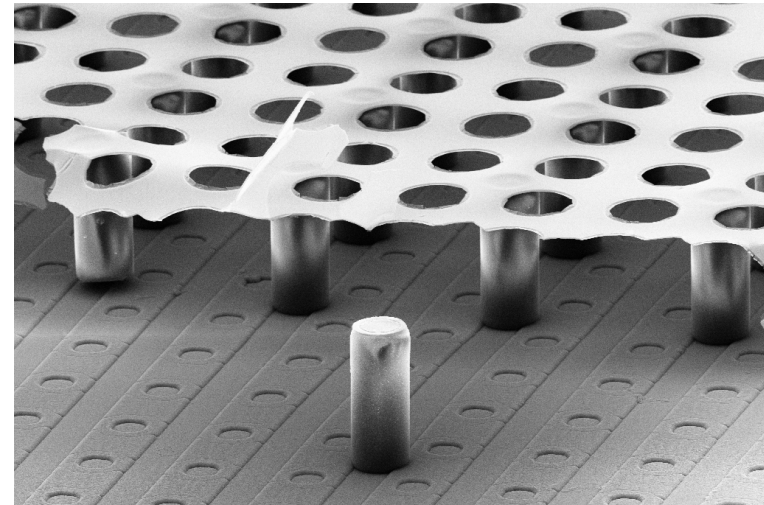
Mag = 58 X Signal A = SE2 Stage at T = 60.0 °
WD = 19 mm EHT = 20.00 kV Chamber = 7.43e-004 Pa Fraunhofer IZM



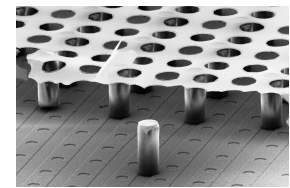
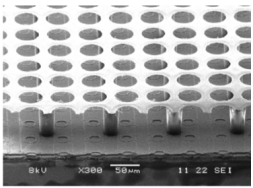
Mag = 324 X Signal A = SE2 Stage at T = 70.1 °
WD = 18 mm EHT = 20.00 kV Chamber = 4.07e-004 Pa Fraunhofer IZM



Mag = 174 X Signal A = SE2 Stage at T = 0.0 °
WD = 8 mm EHT = 20.00 kV Chamber = 1.31e-003 Pa Fraunhofer IZM



Mag = 303 X Signal A = SE2 Stage at T = 70.1 °
WD = 18 mm EHT = 20.00 kV Chamber = 7.23e-004 Pa Fraunhofer IZM



Performance

First batch (10/2011): Problems with resistive layer and Al-grid

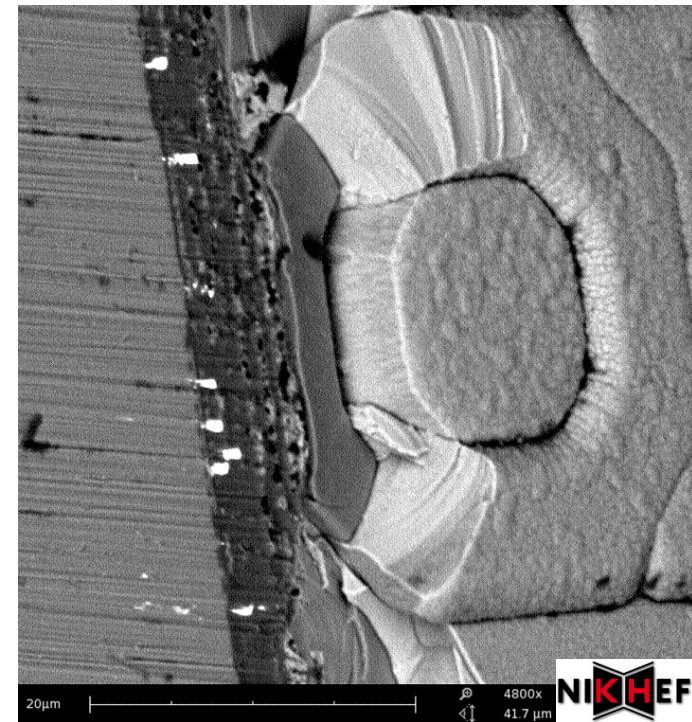
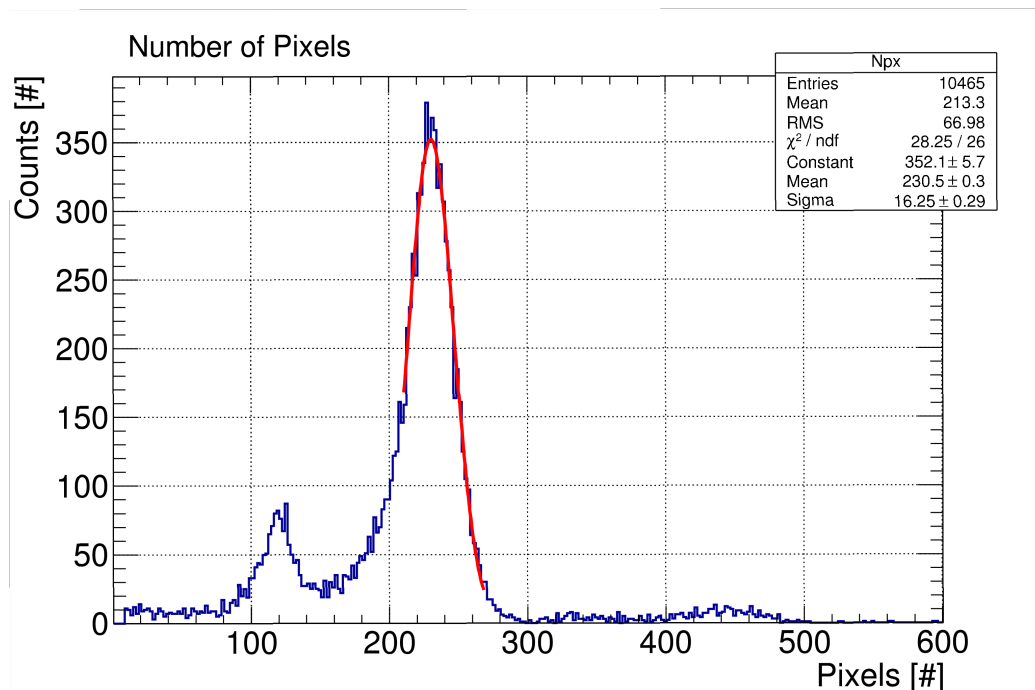
Second batch: Very good optical results, InGrids work well

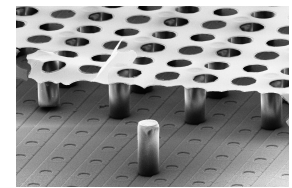
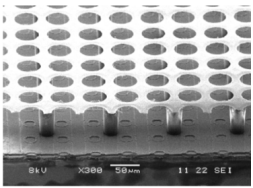
(12/2011) Good energy resolution ($\sigma_E/E \sim 7\%$) and homogeneity

Pillars higher than expected (70-80 μm)

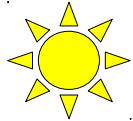
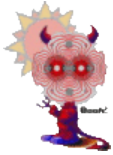
Resistive layer needs optimization (chips die after 2 weeks)

Third batch: in preparation



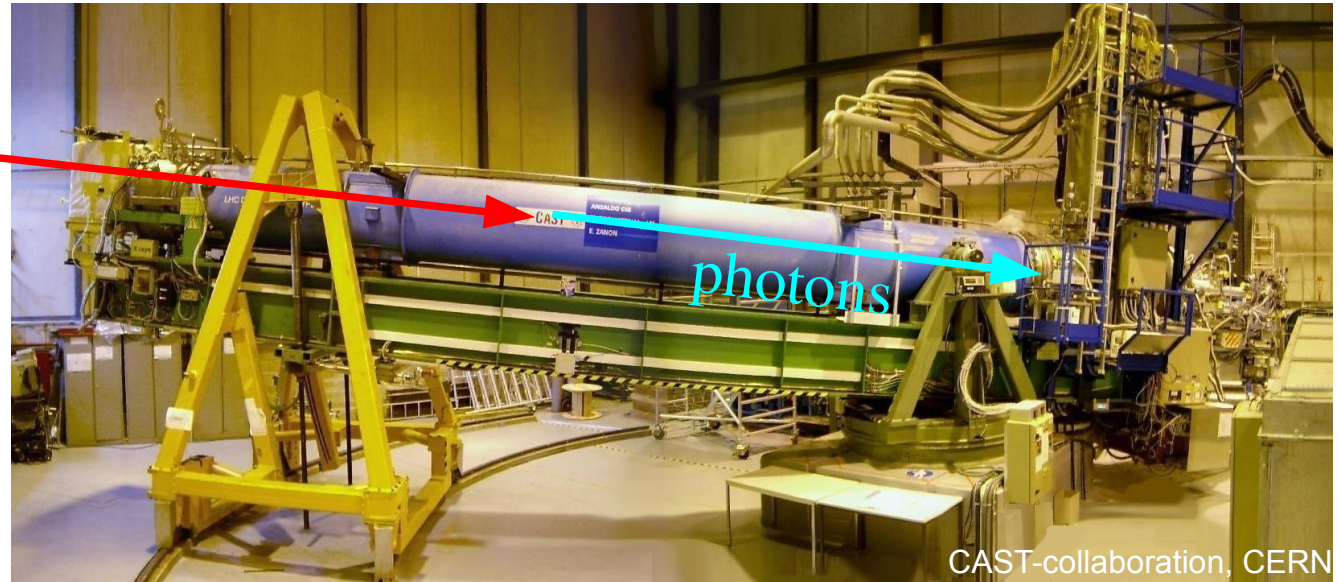


Application CAST

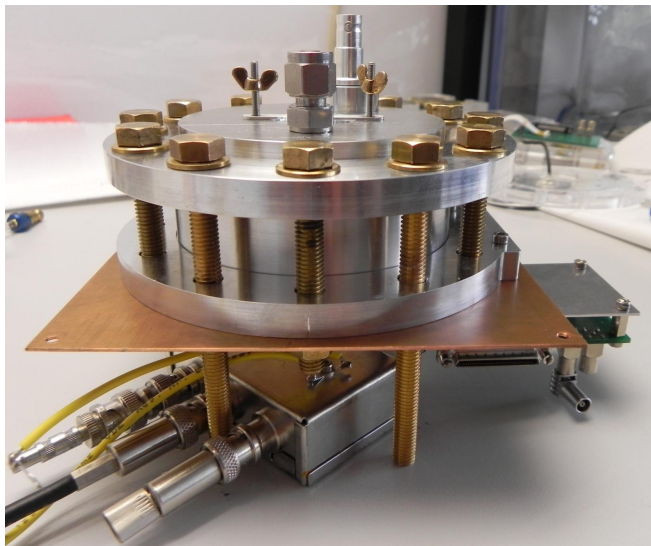


axions

Decommissioned LHC-magnet is pointed to the sun. Axions produced in the sun convert into X-ray photons.



CAST-collaboration, CERN

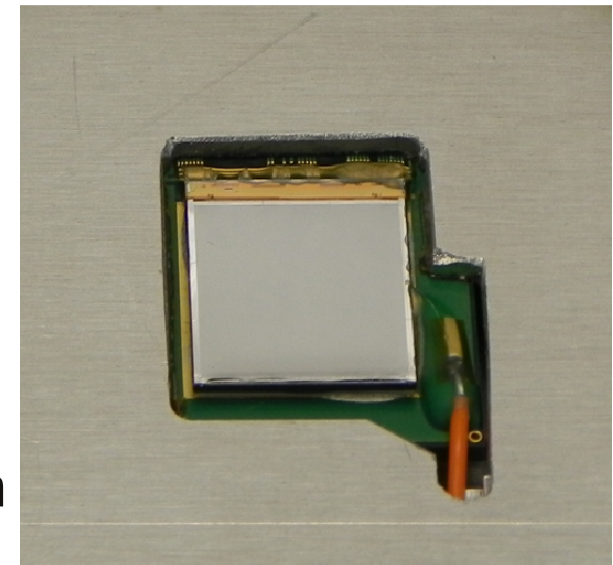


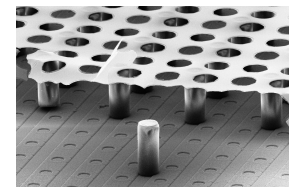
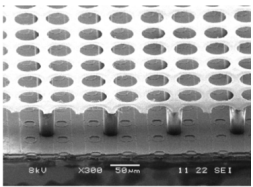
Detect X-rays with high efficiency.

→ Ar-mixture, 1-2 bar, 2 cm conversion volume

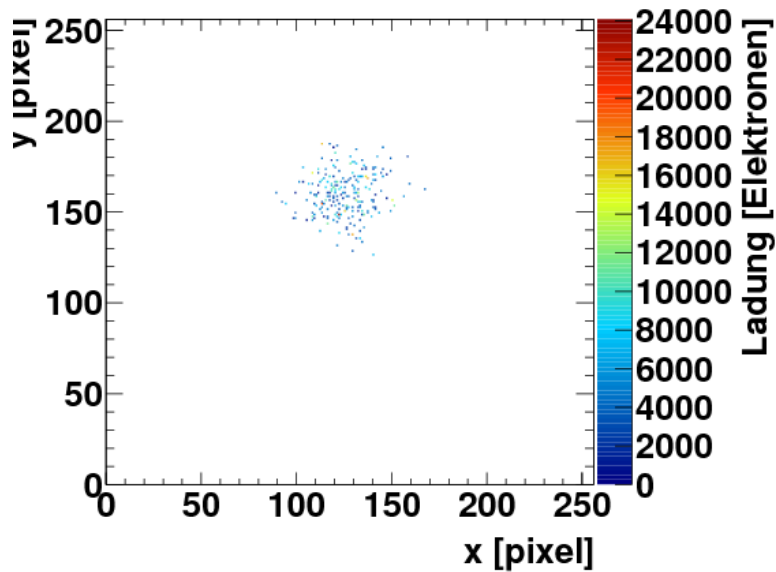
Suppress background as much as possible

→ radiopure material
lead absorber, distinguish tracks from γ s

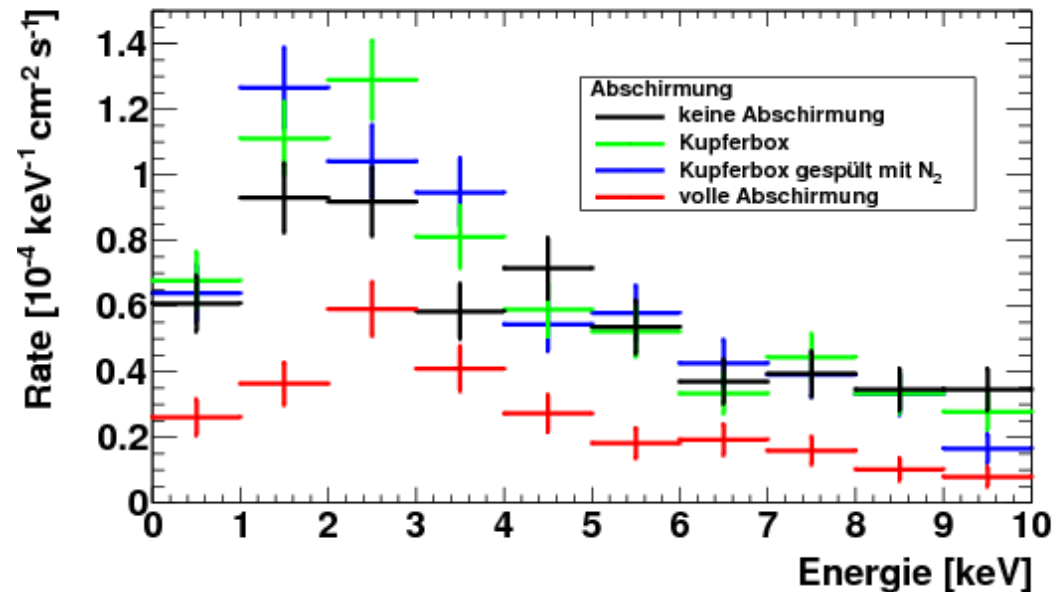
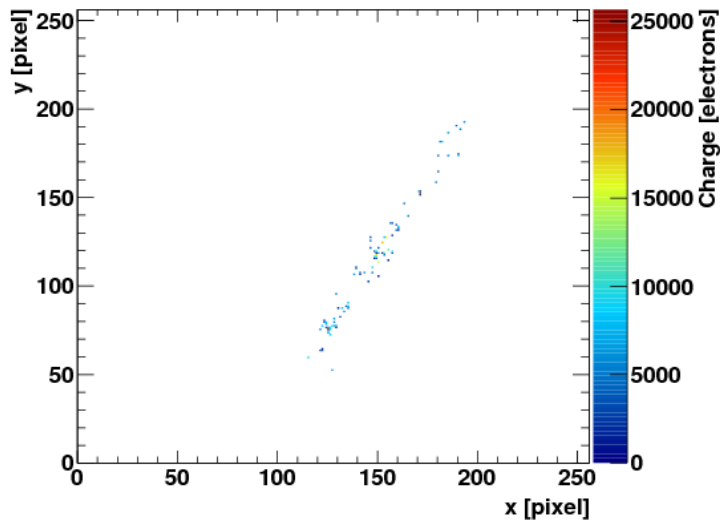
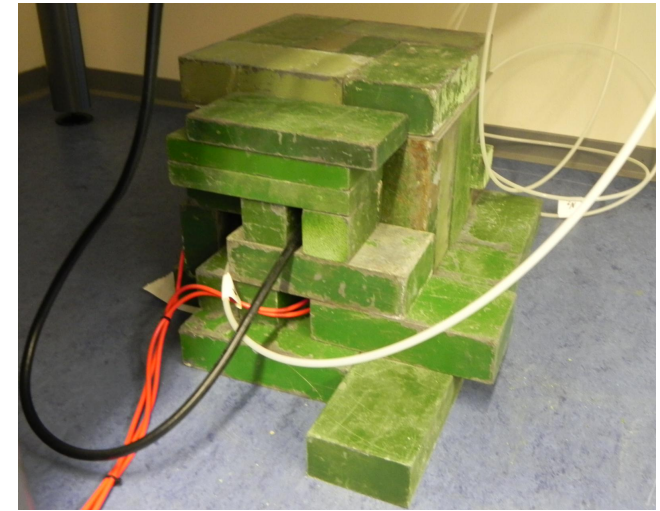


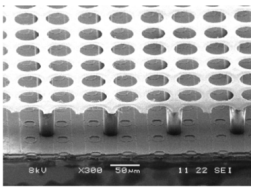


Application CAST

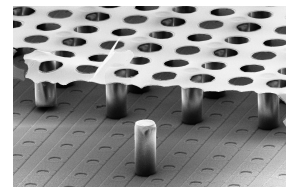


Lead shielding and likelihood ratio algorithm suppress background down to $10^{-5} \text{ keVcm}^{-2}\text{s}^{-1}$





Application LCTPC



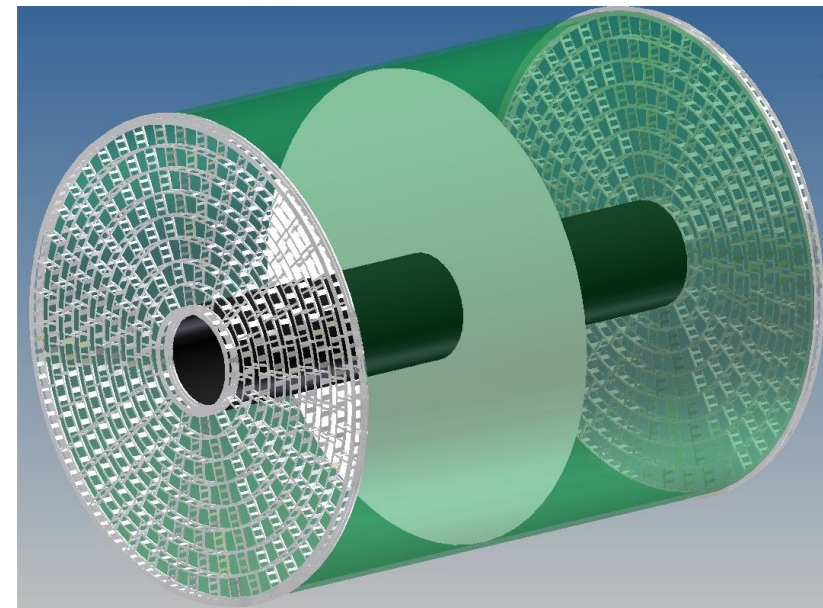
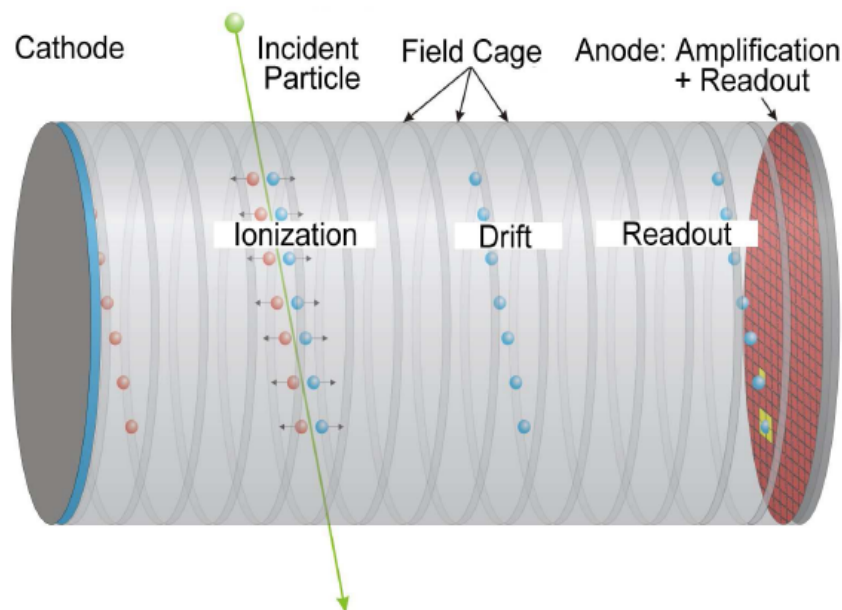
The ILC or CLIC are possible successors of the LHC colliding e^+ and e^- at 300 GeV – 3 TeV. One of the two detector concepts foresees a large **Time Projection Chamber** as a central tracking device. Micropattern gas amplification stages are needed to fulfill requirements.

size of endcaps $\sim 10 \text{ m}^2$

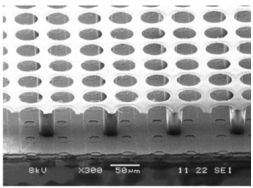
8 rows of MPGD detector modules;

module size $\sim 17 \times 22 \text{ cm}^2$

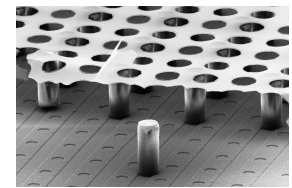
240 modules per endcap



To readout TPC with InGrids, one needs ~ 100 chips per module \rightarrow 2000-2500 per endcap



Application LCTPC



Test setup at U. of Bonn

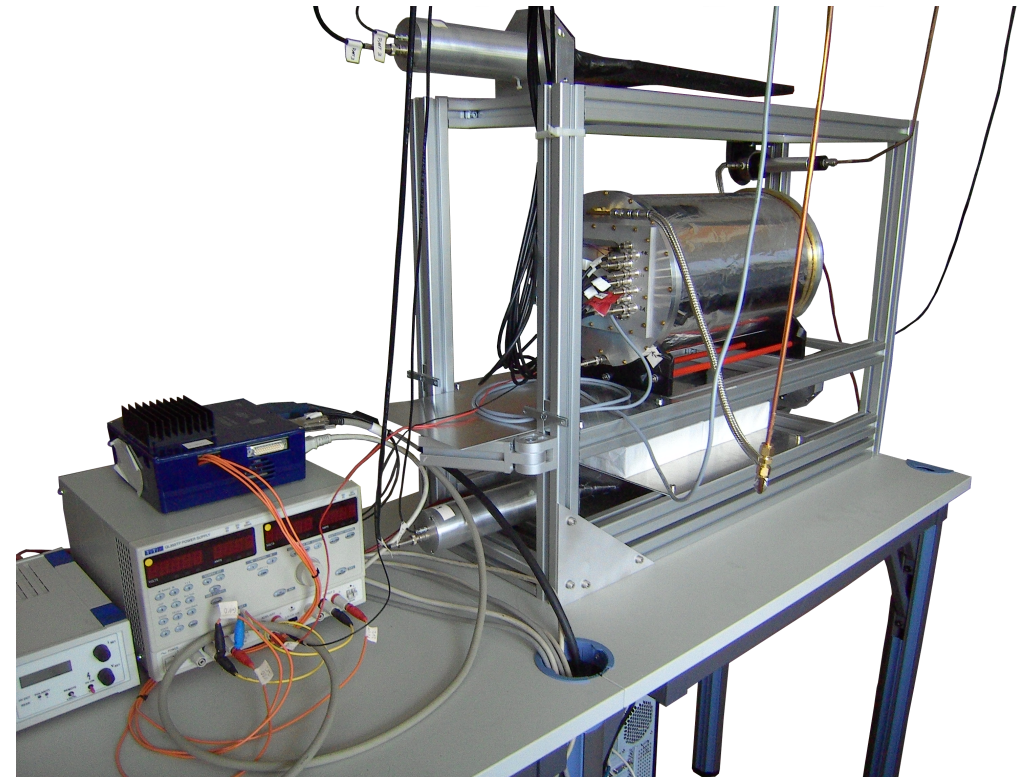
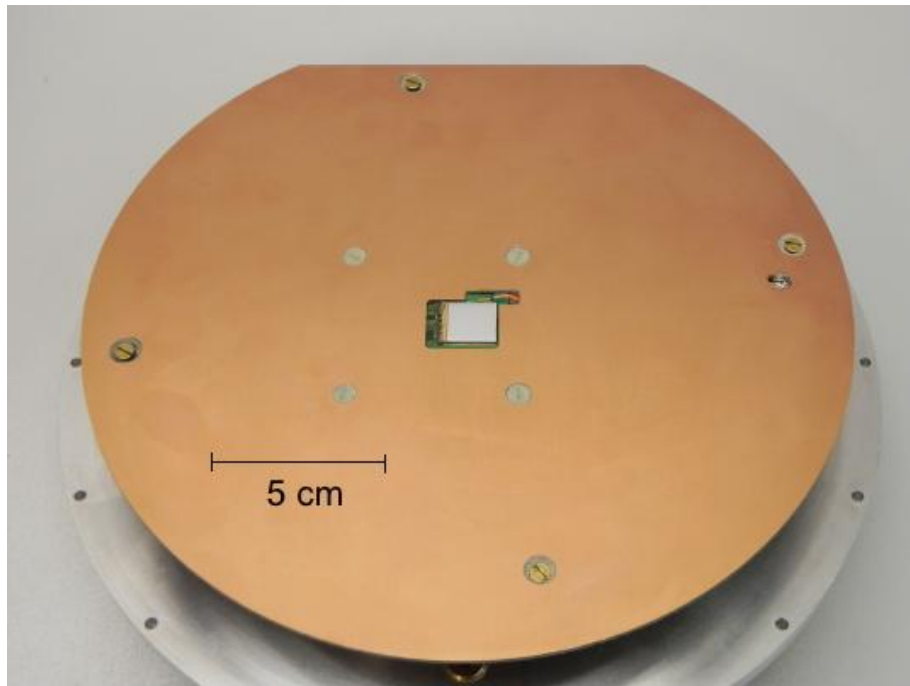
Triggered by two scintillators

Max. drift length: 26 cm

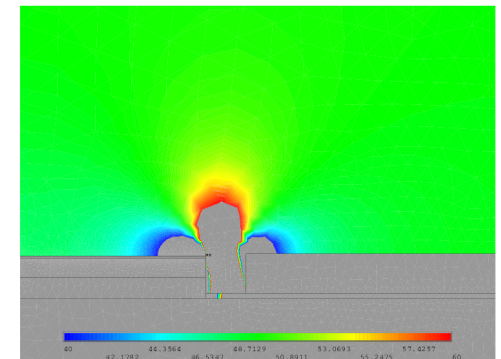
Measures cosmic muons

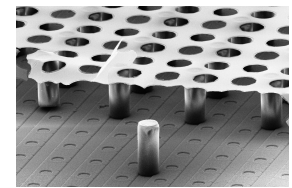
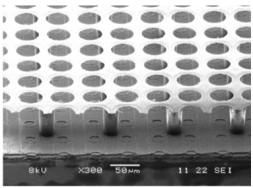
Drift field: 450 V/cm

Gas: He:CO₂ (70:30)

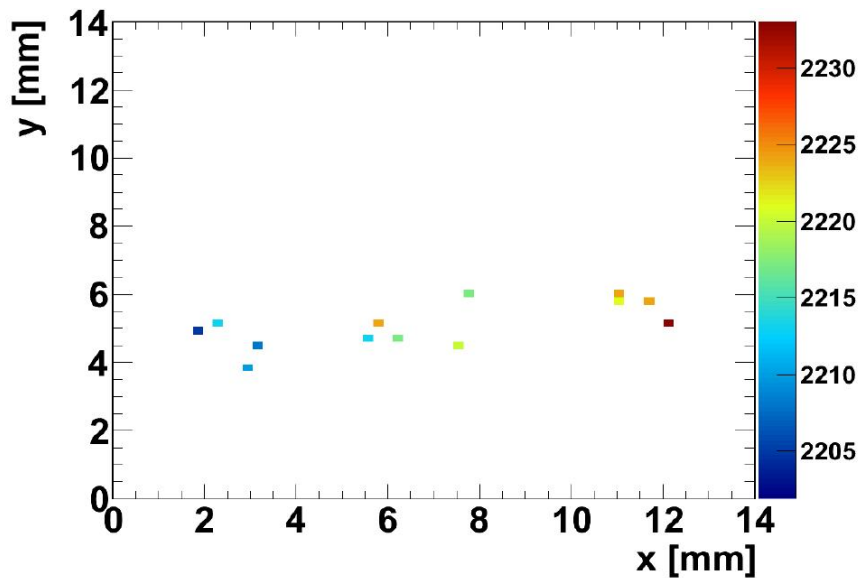


Field distortions
originating from
gap between chip
and termination
plate





Application LCTPC



For the analysis only the **area with no field distortions** was used. Larger areas, first an 8 chip module then an 100 chip module are planned. The **gaps** between chips must be made **smaller** in these modules.

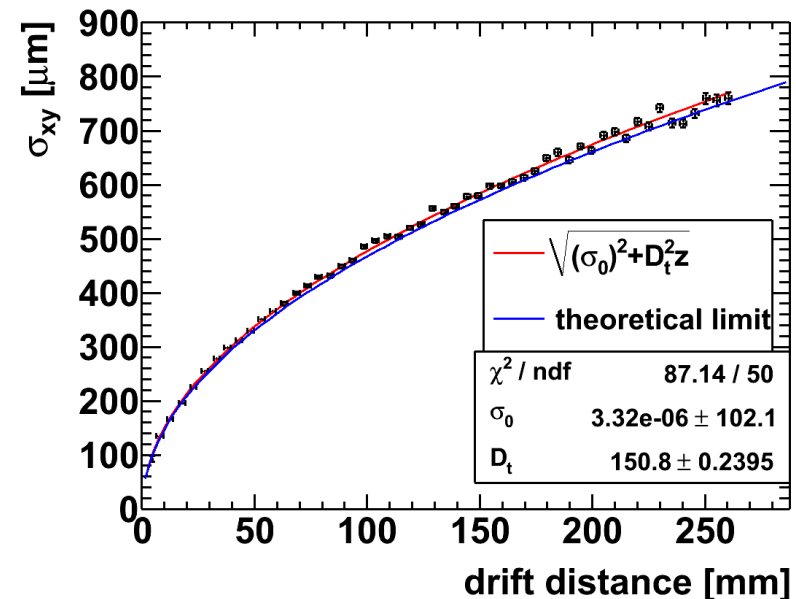
Transverse spatial resolution **right on diffusion limit of single electrons.**

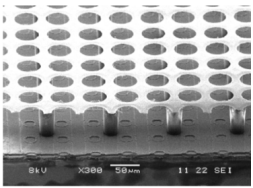
Theoretical limit:

$$\sigma = D_t \sqrt{z}$$

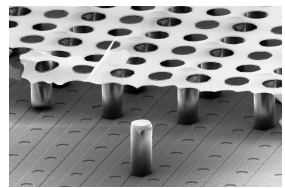
with diffusion coefficient

D_t calculated with Magboltz.





Industrial Application



Still struggling on the academic level 😊,
but there is already one idea for industrialization:

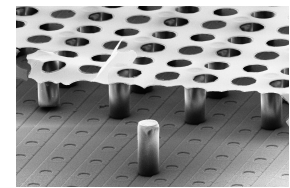
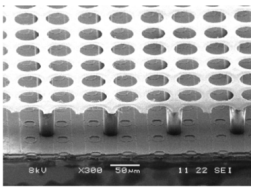
A demonstrator TPC for educational purposes (for example schools)

This model could be based on 4 InGrids
read out with the ReLaXd electronics
a 5-10 cm drift volume
with Scintillator as triggering device
- possibly a magnetic field by permanent magnet

But this project needs funding!

- Needs one or two people to work full time (PhD.)

A first try for funding from the Dutch government was done by NIKHEF
and U. Twente - but failed.



Summary and Outlook

InGrids have shown excellent performance:

Energy resolution of $\sigma_E/E \sim 5\%$ (at 5.9 keV)

Spatial resolution only limited by diffusion.

High efficiency for single electron detection.

Production techniques are well advanced, a few details (protection layer in particular) have to be optimized.

Several readout systems optimized for compactness, speed or large systems have been developed and are commercially available.

Large systems (~100 chips) will be operated next year

Further R&D on InGrids are planned (resistive grid, all ceramic,...)

New Timepix-3 should be available next year.

Acknowledgment: This presentation shows the work of many people at NIKHEF, U. Twente/MESA+, U. Bonn, IZM, CEA Saclay.

I would like to mention in particular:

Yevgen Bilevich, who makes the InGrids, and

Cristoph Krieger, whose detector is used in the demonstration.